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\*\* CONTINUING DATA \*\*\*\*\* *DSP Non*\*\* FOREIGN APPLICATIONS \*\*\*\*\* *P*

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Verified and Acknowledged	Examiner's Signature <i>[Signature]</i>	Initials <i>[Initials]</i>			

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## TITLE

Method of manufacturing capacitor of semiconductor device by simplifying process of forming dielectric layer and apparatus therefor

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